

Manz Digital Printer SDC100

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Technical Specifications

SDC100

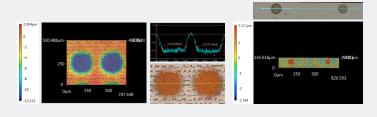
02 0200		
Max. Substrate Size	350 mm x 350 mm (adopt 12" wafer or smaller)	
Footprint (W x D x H)	2.5 m x 2.5 m x 1.9 m	
Weight	4,300 kg	
Substrate clamping	Vacuum	
Base Frame	Granite	
Stage	Accuracy	\pm 1 μ m
	Precision	$\pm~0.5\mu{\rm m}$
Print speed	800 mm / sec	
Available Printheads	Konica Minolta / Epson / Fujifilm / Xaar / Ricoh / Kyocera / Toshiba *note: 1 upto 3 printheads integration available.	
Vision system (option)	 Drop watch for droplet path, drop volume and speed evaluation. CCD for position detection, printed image view, pattern inspection. UV light as ink curing module. 	
Applicable Substrate material	PET / Glass / Wafer / PI / LCP With min. thickness 0.3 mm , Max thickness 20 mm.	
Available Functional ink	Solvent / Water / UV	
Viscosity range	10~20 m Pa · Sec	

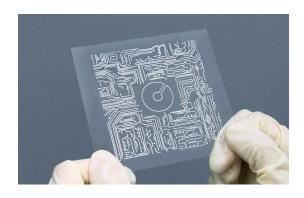
Note

(1) Chart of applications and corresponded ink type.

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Electronics Conductive layer, Dielectrics layer	Ag / Cu conductive ink
Resists Etching resist, Plating resist, Solder resist	UV type black / green resist ink
Optics Black Matrix, Anti-refection, Anti-scratch	UV / solvent type black ink

(2) Solder mask for patterned coverage on copper redistribution layers. Target clearance diameter is 230 μ m & diameter accuracy \pm 4 μ m





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Features

- Offers versatile functional printing for customization applications. (1)
- Ensures precise printing with good dot and space definition in the X/Y direction, achieving a drop accuracy of $\pm 10~\mu m$ @ 3 sigma. (2)
- Features a user-friendly GUI supporting
 *.TIFF and DXF file formats with a maximum printing resolution of 5400 dpi.
- Enables high-speed printing at 800 mm/ sec, and offers multiple printheads with interlaced nozzles to achieve higher resolution and throughput.
- Features a stable granite structure with a CDA antivibration system for damping.
- Precision mechanical design with selfcalibration, including nozzle calibration.
- HEPA assembly prevents dust and contamination in compliance with class 100~1000 regulations, tailored for semiconductor manufacturing.
- Additive processes enhance production efficiency and sustainability.
- Upon request, add-on modules such as UV light, dropwatch, and CCD can be included.